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Sheet 3 of 3

**Complete if Known**

Application Number	09/893,340
Filing Date	June 26, 2001
First Named Inventor	Kang, Sien G.
Art Unit	2813
Examiner Name	Erik J. Kielin
Attorney Docket Number	018419-008320US

**OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS**

Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
EK	40	Centura Epi "Epitaxial Deposition Chamber Specifications" Brochure, Applied Materials, March 1994.	
EK	41	EPI CENTURA System Specifications Brochure, Applied Materials, October 1996.	
EK	(42)	MAHAJAN et al., <i>Principles of Growth and Processing of Semiconductors</i> , WCB McGraw-Hill, chapter 6, pgs. 262-269. 1999	✓
EK	43	SATO et al., "Suppression of Si Etching during Hydrogen Annealing of Silicon-on-Insulator," <i>Proceedings 1998 IEEE SOI Conference</i> , pgs. 17-18, from conference of 10/5-8/98.	
EK	(44)	SMITH, D.L., <i>Thin-Film Deposition</i> , McGraw-Hill, Inc., pgs. 185-196, 278-293. 1995	
EK	(45)	TONG et al., <i>Semiconductor Wafer Bonding: Science and Technology</i> , John Wiley & Sons, Inc., pgs. 152-171. 1999	✓

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Examiner Signature	<i>Erik Kielin</i>	Date Considered	10/28/03
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